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Information Disclosure Citation  
In an Application

Application No.  
10/849,192

Applicant(s)  
Mohammed N. Islam et al.

Docket Number  
074036.0127

Group Art Unit  
2872

Filing Date  
August 27, 2003

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U.S. PATENT DOCUMENTS

	DOCUMENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
A						
B						
C						
D						
E						
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K						
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M						

FOREIGN PATENT DOCUMENTS

	DOCUMENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO
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R	W.R. Wieszniowski et al., "Mechanical Light Modulator Fabricated on a Silicon Chip using SImox Technology," pp. 1027-1030	December 1996
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EXAMINER *Galyn Jula* DATE CONSIDERED *4 AUGUST 2004*

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<b>Information Disclosure Citation in an Application</b>		Application No. <b>10/649,192</b>		Applicant(s) <b>Mohammad N. Islam et al.</b>	
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		Filing Date <b>August 27, 2003</b>			

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EXAMINER <i>Johanna Zula</i>	DATE CONSIDERED <b>4 AUGUST 2004</b>
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